



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

**Applicants:** Yong-Pil Han et al.

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**For:** HF Vapor Phase Wafer Cleaning and Oxide Etching

**Confirmation No.:** 8629

**Art Unit:** 1763

**Examiner:** R. P. Culbert

**BOX ISSUE FEE**

**ASSISTANT COMMISSIONER FOR PATENTS**

**WASHINGTON, DC 20231**

**Mailing Date of Notice of Allowance: December 17, 2003**

**Confirmation Number: 8629**

I hereby certify under 37 CFR 1.8(a) that this correspondence is being deposited on the date shown below with the United States Postal Service in an envelope with sufficient postage as First Class Mail addressed to: Mail Stop Issue Fee, Commissioner For Patents P.O. Box 1450, Alexandria, VA 22313-1450

*Theresa A. Lober*  
March 10, 2004

**RESPONSE TO NOTICE OF ALLOWANCE**

In response to the Notice of Allowance mailed December 17, 2003, herewith are provided the following:

- Completed Issue Fee Transmittal Form PTOL-85
- Authorization to charge the amount of \$1350.00 to cover the issue fee and advance order copy fee to Deposit Account No. 19-2553
- Authorization to charge any deficiency in stated fees, and to apply credits to Deposit Account No. 19-2553
- Copy of the completed Form PTOL-85B
- Change of Correspondence Address Form PTO/SB/122

Respectfully submitted,

Date:

*March 10, 2004*  
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